

*VORTEX UNIT FOR PROVIDING A DESIRED ENVIRONMENT
FOR A SEMICONDUCTOR PROCESS*

ABSTRACT

A vortex unit suitable for providing a desired environment for a semiconductor process may include a vortex tube and a semiconductor processing device suitable for performing a semiconductor processing function. The vortex tube includes an air inlet for receiving compressed air, a first air exhaust for outputting an air stream having a temperature greater than the received compressed air, and a second air exhaust for outputting an air stream having a temperature lower than the received compressed air. The semiconductor processing device is connected to the second air exhaust of the vortex tube so that the semiconductor processing device receives a cooled air stream from the vortex tube, the cooled air stream providing an environment suitable for enabling the semiconductor processing device to perform the semiconductor processing function.